

PATENT ASSIGNMENT COVER SHEET

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	CHANGE OF NAME
CONVEYING PARTY DATA	
Name	Execution Date
MCUBE, INC.	10/31/2022
RECEIVING PARTY DATA	
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Street Address:	2570 NORTH FIRST STREET
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State/Country:	CALIFORNIA
Postal Code:	95131
PROPERTY NUMBERS Total: 1	
Property Type	Number
Application Number:	13008870
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NAME OF SUBMITTER:	ANNE OLSEN
SIGNATURE:	/ANNE OLSEN/
DATE SIGNED:	10/31/2022
Total Attachments: 9	
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ASSIGNMENT OF PATENT APPLICATION

WHEREAS, Dennis Calderon, of mCube, Inc., hereinafter referred to as "ASSIGNOR," is an assignee by assignment recorded in the U.S. Patent and Trademark Office of the inventions described and set forth in the Applications for United States Letters Patent and United States Letters Patent identified in the Appendices attached hereto;

WHEREAS, Dennis Calderon, General Counsel and authorized representative at mCube, Inc. is a duly authorized representative of mCube, Inc. having authority to sell, assign, and transfer to a third party the below-identified Applications for United States Letters Patent and United States Letters Patent in the Appendix attached hereto.


WHEREAS, Dennis Calderon, of Movella Inc. hereinafter referred to as "ASSIGNEE," is desirous of acquiring an entirety of ASSIGNOR'S interest in the said inventions and applications and in any U.S. Letters Patent which may be granted on the same;

NOW, THEREFORE, TO ALL WHOM IT MAY CONCERN: Be it known that, for good and valuable consideration, receipt of which is hereby acknowledged by Assignor, Assignor has sold, assigned and transferred, and by these presents does sell, assign, and transfer unto the said Assignee, and Assignee's successors and assigns, 100% of their right, title, and interest in and to the said inventions, application, and U.S. Letters Patent including any corresponding foreign application, and in and to any Letters Patent which may hereafter be granted on the same in the United States and any corresponding foreign application, the said interest to be held and enjoyed by said Assignee as fully and exclusively as it would have been held and enjoyed by said Assignor had this Assignment and transfer not been made, to the full end and term of any Letters Patent which may be granted thereon, or of any division, renewal, continuation in whole or in part, substitution, conversion, reissue, prolongation or extension thereof.

Assignor further agree that they will, without charge to Assignee, but at Assignee's expense, cooperate with Assignee in the prosecution of said application and/or applications, execute, verify, acknowledge and deliver all such further papers, including applications for Letters Patent and for the reissue thereof, and instruments of assignment and transfer thereof, and will perform such other acts as Assignee lawfully may request, to obtain or maintain Letters Patent for said invention and improvement, and to vest title thereto in Assignee, or Assignee's successors and assigns.

IN TESTIMONY WHEREOF, Assignor has signed this Assignment on the date indicated.

10/31/22
Date: _____


Name: Dennis Calderon
Title: General Counsel

APPENDIX A

(U.S. Patents and Patent Applications)

Title of Invention	Application Number	Filing Date	Patent Number	Issue Date
METHOD AND STRUCTURE OF MEMS PLCSF FABRICATION	15647107	11-Jul-2017	9975759	22-May-2018
MULTI-LAYER SINGLE CHIP MEMS WLCSP FABRICATION	15787532	18-Oct-2017	10106399	23-Oct-2018
LOW POWER ROTATIONAL DETECTION METHODS AND APPARATUS	16101276	10-Aug-2018	10845379	24-Nov-2020
MEMS DEVICE WITH STICTION RECOVER AND METHODS	15877999	23-Jan-2018	10961119	30-Mar-2021
DIFFERENTIAL MEMS DEVICE AND METHODS	16530923	02-Aug-2019	11255871	22-Feb-2022
UMBRELLA, UMBRELLA PERIPHERAL AND METHODS	16534978	07-Aug-2019	10561210	18-Feb-2020
PORTABLE COMPUTING DEVICE AND METHODS	16655124	16-Oct-2019	11009908	18-May-2021
DYNAMIC OFFSET CORRECTION FOR CALIBRATION OF MEMS SENSOR	13760014	05-Feb-2013	10324108	18-Jun-2019
METHOD OF FABRICATING MEMS DEVICES USING PLASMA ETCHING AND DEVICE THEREFOR	14658114	13-Mar-2015	10913653	09-Feb-2021
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED INERTIAL SENSOR USING IC FOUNDRY-COMPATIBLE PROCESSES	12717070	03-Mar-2010	8227285	24-Jul-2012
METHOD AND STRUCTURE OF WAFER LEVEL ENCAPSULATION OF INTEGRATED CIRCUITS WITH CAVITY	12634663	09-Dec-2009	8227911	24-Jul-2012
Foundry compatible process for manufacturing a magneto meter using lorentz force for integrated systems	13007574	14-Jan-2011	8236577	07-Aug-2012

Security system and methods for integrated devices	13762237	07-Feb-2013	9418247	16-Aug-2016
Three axis magnetic sensor device and method using flex cables	14606909	27-Jan-2015	9423473	23-Aug-2016
System on a chip using integrated MEMS and CMOS devices	14445012	28-Jul-2014	9440846	13-Sep-2016
METHOD OF REDUCING GYROSCOPE OSCILLATOR START-UP TIME AND DEVICE THEREFOR	14497317	25-Sep-2014	9464899	11-Oct-2016
METHOD AND STRUCTURE OF AN INTEGRATED CMOS AND MEMS DEVICE USING AIR DIELECTRIC	12945846	13-Nov-2010	8324047	04-Dec-2012
METHOD AND APPARATUS FOR PATTERNING MICRO AND NANO STRUCTURES USING A MASK-LESS PROCESS	11558441	09-Nov-2016	7473912	06-Jan-2009
METHOD AND STRUCTURE OF MEMS WLCSP FABRICATION	14507177	06-Oct-2014	9540232	10-Jan-2017
METHOD AND STRUCTURE FOR AN OUT-OF PLANE COMPLIANT MICRO ACTUATOR	11555063	31-Oct-2006	7498715	03-Mar-2009
METHOD AND DEVICE FOR MAGNETORESISTIVE SENSOR	13757426	01-Feb-2013	9588194	07-Mar-2017
INTEGRATED MEMS AND CMOS PACKAGE AND METHOD	12945087	12-Nov-2010	8395252	12-Mar-2013
SINGLE POINT OFFSET CALIBRATION FOR INERTIAL SENSORS	13936117	05-Jul-2013	9594095	14-Mar-2017
METHOD AND STRUCTURE OF THREE DIMENSIONAL CMOS TRANSISTORS WITH HYBRID CRYSTAL ORIENTATIONS	14218633	18-Mar-2014	9595479	14-Mar-2017
MAGNETO METER USING LORENTZ FORCE FOR INTEGRATED SYSTEMS	12957222	30-Nov-2010	8402666	26-Mar-2013
ANCHOR DESIGN AND METHOD FOR MEMS TRANSDUCER APPARATUSES	12859647	19-Aug-2010	8553389	08-Oct-2013

PACKAGE TOLERATE DESIGN AND METHOD	13090234	19-Apr-2011	8564075	22-Oct-2013
METHOD AND STRUCTURE FOR KINETIC ENERGY BASED GENERATOR FOR PORTABLE ELECTRONIC DEVICES	11555101	31-Oct-2006	7608933	27-Oct-2009
METHOD AND STRUCTURE OF WAFER LEVEL ENCAPSULATION OF INTEGRATED CIRCUITS WITH CAVITY	13542637	05-Jul-2012	8569180	29-Oct-2013
ACCURATE GYROSCOPE DEVICE USING MEMS AND QUARTZ	13008865	18-Jan-2011	8584521	19-Nov-2013
METHOD AND STRUCTURE OF INTEGRATED MICRO ELECTRO-MECHANICAL SYSTEMS AND ELECTRONIC DEVICES USING EDGE BOND PADS	13751014	25-Jan-2013	8592993	26-Nov-2013
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED MICRONEEDLE BIOCHIP	12634638	09-Dec-2009	8506529	13-Aug-2013
MULTIPLE MAGNETO METERS USING LORENTZ FORCE FOR INTEGRATED SYSTEMS	13007585	14-Jan-2011	8407905	02-Apr-2013
INTEGRATED CMOS AND MEMS WITH AIR DIELECTRIC METHOD AND SYSTEM	13008870	18-Jan-2011	8421082	16-Apr-2013
Touchscreen operation threshold methods and apparatus	12787200	25-May-2010	8643612	04-Feb-2014
Methods and structure for adapting MEMS structures to form electrical interconnections for integrated circuits	13164311	20-Jun-2011	8652961	18-Feb-2014
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED IC-MEMS OSCILLATOR USING IC FOUNDRY-COMPATIBLE PROCESSES	13311538	05-Dec-2011	8704238	22-Apr-2014
METHOD AND STRUCTURE FOR ADDING MASS WITH STRESS ISOLATION TO MEMS STRUCTURES	13090228	19-Apr-2011	8710597	29-Apr-2014

METHOD AND STRUCTURE FOR AN OUT-OF-PLANE COMPLIANT MICRO ACTUATOR	12353969	15-Jan-2009	7928632	19-Apr-2011
METHODS AND APPARATUS FOR FACILITATING CAPTURE OF MAGNETIC CREDIT CARD DATA ON A HAND HELD DEVICE	12940020	04-Nov-2010	8181874	22-May-2012
METHOD AND STRUCTURES OF MONOLITHICALLY INTEGRATED ESD SUPPRESSION DEVICE	12511002	28-Jul-2009	8148781	03-Apr-2012
MULTI-AXIS INTEGRATED MEMS DEVICES WITH CMOS CIRCUITS AND METHOD THEREFOR	12983309	02-Jan-2011	8637943	28-Jan-2014
METHODS AND APPARATUS FOR INITIATING IMAGE CAPTURE ON A HAND-HELD DEVICE	12940025	04-Nov-2010	8723986	13-May-2014
METHOD AND STRUCTURE OF SENSORS OR ELECTRONIC DEVICES USING VERTICAL MOUNTING	13922983	20-Jun-2013	8749004	10-Jun-2014
THREE AXIS MAGNETIC SENSOR DEVICE AND METHOD	13924457	21-Jun-2013	8742520	03-Jun-2014
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED MICROMACHINED MICROPHONE USING IC FOUNDRY-COMPATIBLE PROCESSES	12490292	23-Jun-2009	8796790	05-Aug-2014
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED PRESSURE SENSOR USING IC FOUNDRY-COMPATIBLE PROCESSES	12499027	07-Jul-2009	8796746	05-Aug-2014
Analog Touchscreen Methods and Apparatus	12787368	25-May-2010	8797279	05-Aug-2014
INTEGRATED INERTIAL SENSING APPARATUS USING MEMS AND QUARTZ CONFIGURED ON CRYSTALLOGRAPHIC PLANES	13035968	26-Feb-2011	8794065	05-Aug-2014
INTEGRATED SYSTEM ON CHIP USING MULTIPLE MEMS AND CMOS DEVICES	12913440	27-Oct-2010	8823007	02-Sep-2014

METHOD AND STRUCTURE OF SENSORS AND MEMS DEVICES USING VERTICAL MOUNTING WITH INTERCONNECTIONS	13030871	18-Feb-2011	8476129	02-Jul-2013
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED IC-MEMS OSCILLATOR USING IC FOUNDRY-COMPATIBLE PROCESSES	12634634	09-Dec-2009	8071398	06-Dec-2011
Three Axis Magnetic Sensor Device and Method	12859631	19-Aug-2010	8486723	16-Jul-2013
METHODS AND APPARATUS FOR CAPTURING MAGNETIC CREDIT CARD DATA ON A HAND HELD DEVICE	12940023	04-Nov-2010	8245923	21-Aug-2012
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED INERTIAL SENSOR USING IC FOUNDRY-COMPATIBLE PROCESSES	13494986	12-Jun-2012	8432005	30-Apr-2013
METHOD AND STRUCTURE OF INTEGRATED MICRO ELECTRO-MECHANICAL SYSTEMS AND ELECTRONIC DEVICES USING EDGE BOND PADS	13082384	07-Apr-2011	8367522	05-Feb-2013
METHOD AND STRUCTURE OF SENSORS OR ELECTRONIC DEVICES USING VERTICAL MOUNTING	13113883	23-May-2011	8476084	02-Jul-2013
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED INFRARED SENSING DEVICE	12511004	28-Jul-2009	8120076	21-Feb-2012
METHODS AND APPARATUS FOR OBJECT TRACKING ON A HAND-HELD DEVICE	12940026	04-Nov-2010	8928602	06-Jan-2015
METHODS AND APPARATUS FOR OPERATING HYSTERESIS ON A HAND HELD DEVICE	13069355	22-Mar-2011	8928696	06-Jan-2015
INTEGRATED RF MEMS, CONTROL SYSTEMS AND METHODS	13035969	26-Feb-2011	8936959	20-Jan-2015

THREE AXIS MAGNETIC SENSOR DEVICE AND METHOD USING FLEX CABLES	13211305	17-Aug-2011	8969101	03-Mar-2015
METHOD AND STRUCTURE OF SENSORS AND MEMS DEVICES USING VERTICAL MOUNTING WITH INTERCONNECTIONS	13923011	20-Jun-2013	8981560	17-Mar-2015
METHOD AND DEVICE FOR CALIBRATING A MAGNETOMETER USING PARTIAL SAMPLING	14242838	01-Apr-2014	9677906	13-Jun-2017
MEMS-BASED PROXIMITY SENSOR DEVICE AND METHOD	14194468	28-Feb-2014	9696337	04-Jul-2017
SYSTEM CONFIGURED FOR INTEGRATED COMMUNICATION, MEMS, PROCESSOR, AND APPLICATIONS USING A FOUNDRY COMPATIBLE SEMICONDUCTOR PROCESS	12944712	11-Nov-2010	9709509	18-Jul-2017
OXIDE RETAINER METHOD FOR MEMS DEVICES	13189471	22-Jul-2011	8993362	31-Mar-2015
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED ESD SUPPERSSION DEVICE	13410273	01-Mar-2012	8999835	07-Apr-2015
MULTI-AXIS INTEGRATED MEMS DEVICES WITH CMOS CIRCUITS AND METHOD THEREFOR	14084415	19-Nov-2013	9150406	06-Oct-2015
DISTRIBUTED MEMS DEVICES TIME SYNCHRONIZATION METHODS AND SYSTEM	14102465	10-Dec-2013	9174838	03-Nov-2015
MEMS-BASED DUAL AND SINGLE PROOF-MASS ACCELEROMETER METHODS AND APPARATUS	13761748	07-Feb-2013	9246017	26-Jan-2016
SUBSTRATE CURVATURE COMPENSATION METHODS AND APPARATUS	13745723	18-Jan-2013	9291638	22-Mar-2016
Selective Accelerometer Data Processing Methods and Apparatus	13755487	31-Jan-2013	9335845	10-May-2016
METHOD AND STRUCTURE FOR ADDING MASS WITH STRESS	14217376	17-Mar-2014	9321629	26-Apr-2016

ISOLATION TO MEMS STRUCTURES				
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED ABSOLUTE PRESSURE SENSOR	14311034	20-Jun-2014	9340414	17-May-2016
INTEGRATED CMOS AND MEMS DEVICES WITH AIR DIELECTRICS	13855988	03-Apr-2013	9365412	14-Jun-2016
METHOD FOR FABRICATING A TRANSDUCER APPARATUS	14031041	18-Sep-2013	9376312	28-Jun-2016
SECURITY SYSTEM AND METHODS FOR INTEGRATED DEVICES	15236182	12-Aug-2016	10078112	18-Sep-2018
DEVICE AND METHOD FOR USING TIME RATE OF CHANGE OF SENSOR DATA TO DETERMINE DEVICE ROTATION	14550888	21-Nov-2014	10197587	05-Feb-2019
POWER SAVING METHOD OF OPERATING A PORTABLE COMPUTING DEVICE	14223903	24-Mar-2014	9588569	07-Mar-2017
METHOD AND STRUCTURE OF MEMS PLCSP FABRICATION	14750820	25-Jun-2015	9738510	22-Aug-2017
METHOD AND APPARATUS FOR REAL-TIME MOTION DIRECTION DETECTION VIA ACCELERATION-MAGNETIC FUSION	15194459	27-Jun-2016	10175778	08-Jan-2019
MEMS DEVICE WITH REDUCED DYNAMIC STRESS AND METHODS	14887737	20-Oct-2015	10322926	18-Jun-2019
MULTIPLE MEMS DEVICE AND METHODS	15444162	27-Feb-2017	10605823	31-Mar-2020
DIFFERENTIAL MEMS DEVICE AND METHODS	17667180	8-Feb-2022	N/A	N/A
FLEXIBLE SENSOR SYSTEM AND METHODS	16734234	3-Jan-2020	N/A	N/A
LONG-TERM ANIMAL MONITORING DEVICE AND SYSTEM	17694530	14-Mar-2022	N/A	N/A
REUSABLE EAR TAG	17552205	15-Dec-2021	N/A	N/A

APPENDIX B
(Foreign Patents and Patent Applications)

Title of Invention	Application Number	Filing Date	Patent Number	Issue Date	Country
POWER SAVING METHOD OF OPERATING A PORTABLE COMPUTING DEVICE	103116511	5/9/2014	1626536	6/11/2018	Taiwan
DYNAMIC OFFSET CORRECTION FOR CALIBRATION OF MEMS SENSOR	201310049774.9	2/7/2013	103246366	8/14/2013	China
METHOD AND STRUCTURE OF MONOLITHICALLY INTEGRATED ABSOLUTE PRESSURE SENSOR	103121771	6/24/2014	1528566	4/1/2016	Taiwan
PROXIMITY SENSOR DEVICE AND METHOD BASED ON MEMS	201410221665.5	5/23/2014	104219346	12/1/2017	China
MEMS-BASED PROXIMITY SENSOR DEVICE AND METHOD	103117391	5/16/2014	1509502	11/21/2015	Taiwan